



ALICE

ITS3

Tuesday 29th October 2024

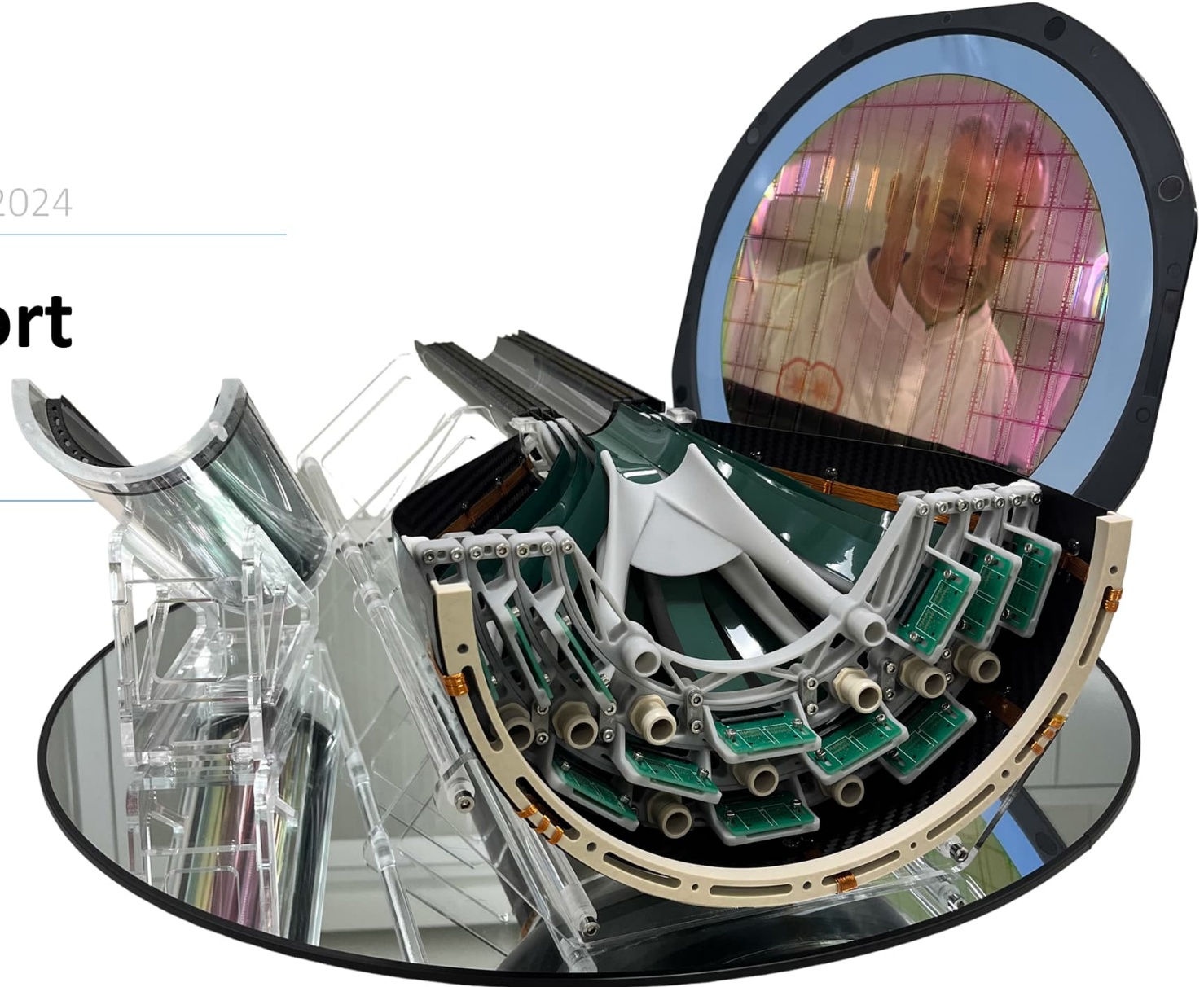
WP5 progress report

M. Angeletti

On behalf of WP5 CERN group

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Utrecht: R. Barthel, J. Deen and Y. Zubaroglu...



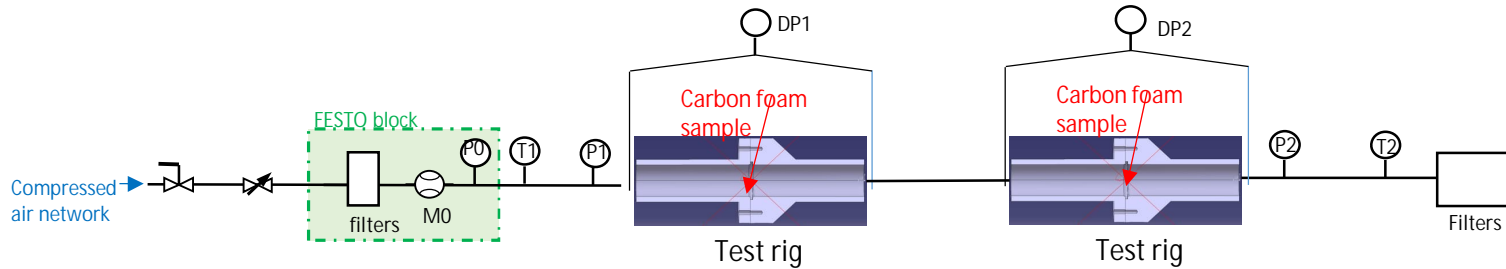
Outline



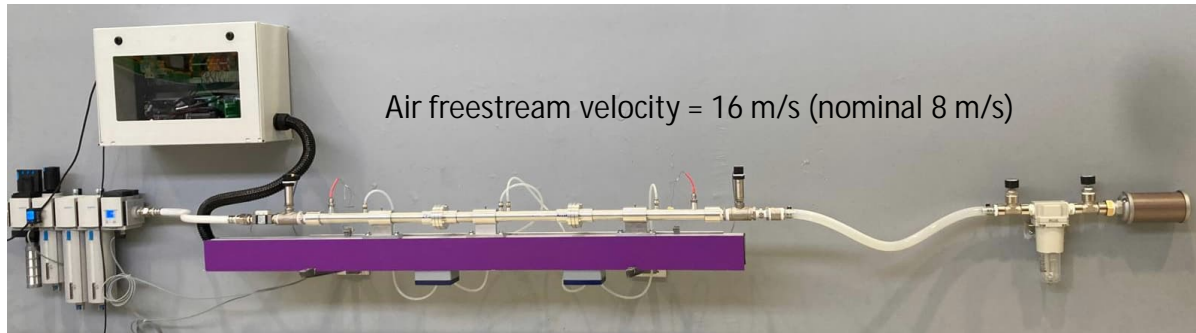
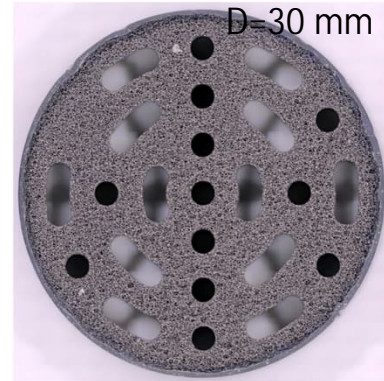
- Tests:
 - Particle realise test
 - Wind-tunnel upgrade
- Prototypes (Engineering Models)
- FPC updates

- Investigate potential particle release and potential degradation of the holes/slots of the carbon foam
- Tests (1 month time) → inspection (visual, check of possible particle inside the vortex filter) → repeat test
- 2 samples : ERG and Allcomp

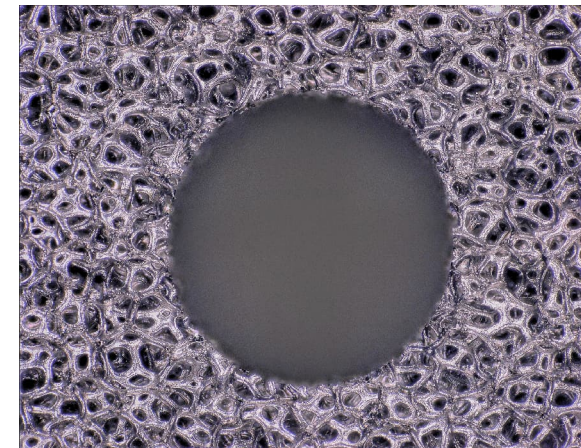
@P. Bouvier, P. Ijzermans, J. Mourot, F. Pellegrino



Visual inspection



-
- Allcomp, 1 month, 10-11 m/s (done)
- ERG, 1 month, 10-11 m/s (done)
- Allcomp, 1 month, 16 m/s (done)
- ERG, 1 month, 16 m/s (done)
- Allcomp+ERG, 1 month, 16 m/s (on-going)
- Allcomp+ERG, 3 months, 16 m/s



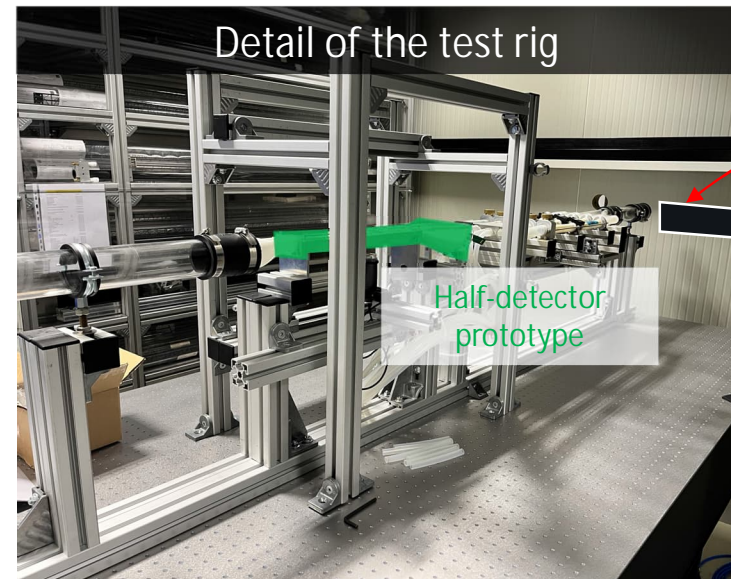
- Release of particles due to the machining (approximately within the first hour of testing).
- No release of particles or potential degradation within 5 months of testing

Tests: Wind-tunnel upgrade

Upgrades to the wind tunnel are being undertaken, which mainly consist of:

- A new isolation table for more precise aeroelastic measurements.
- New compressors and a compressed air line network which both allows extracting and blowing air from A-side

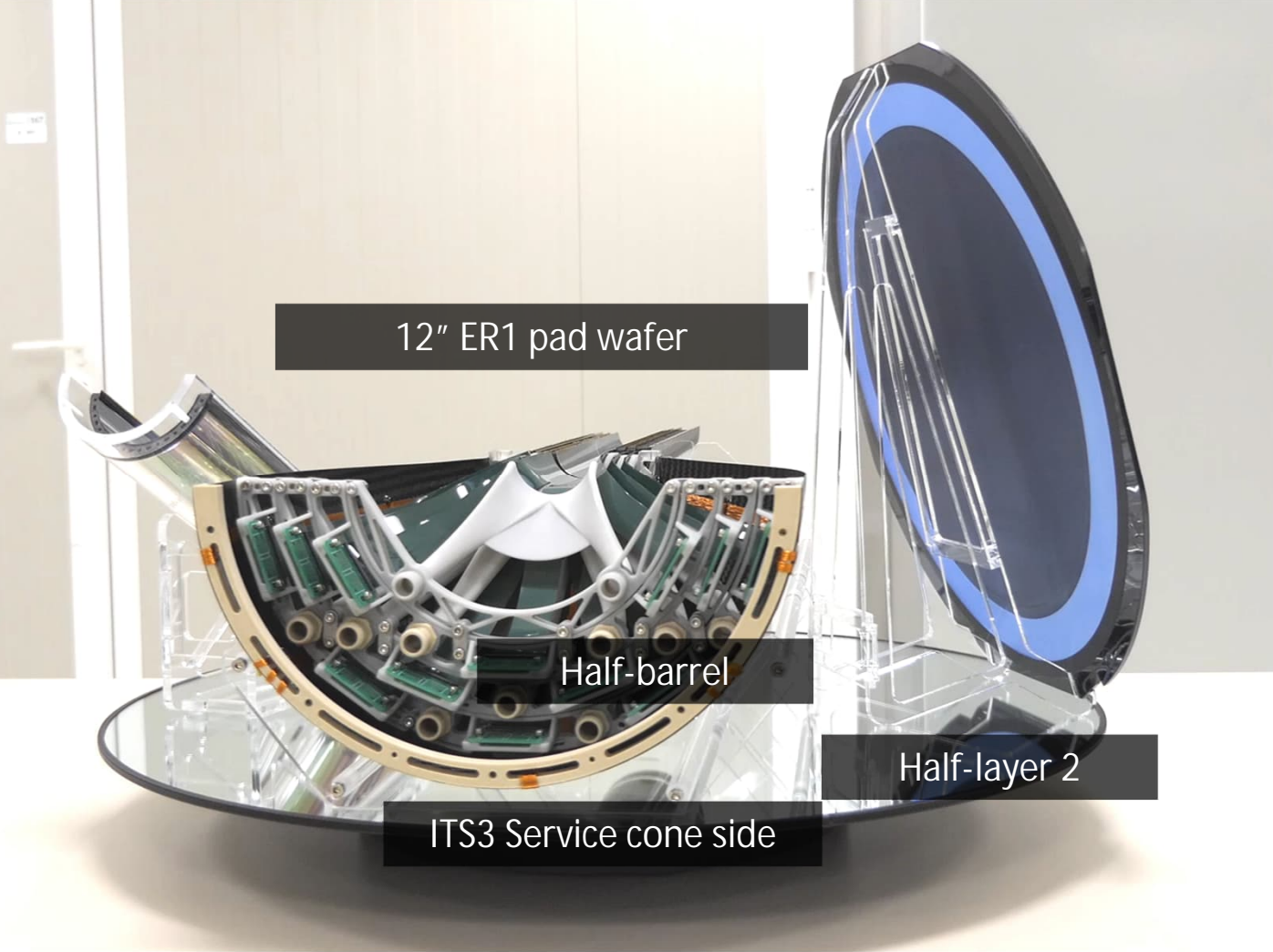
@P. Bouvier, J. Mourot, F. Pellegrino,



Prototypes: CERN70, 1st October exhibition

- On October 1st, an event was held for CERN's 70th anniversary. A small exhibition was prepared, featuring objects representing CERN's activities. One component from each of the four LHC experiments, one from the LHC, and one from IT were included. For ALICE, an ITS3 mockup was displayed.

ALICE ITS3 prototype

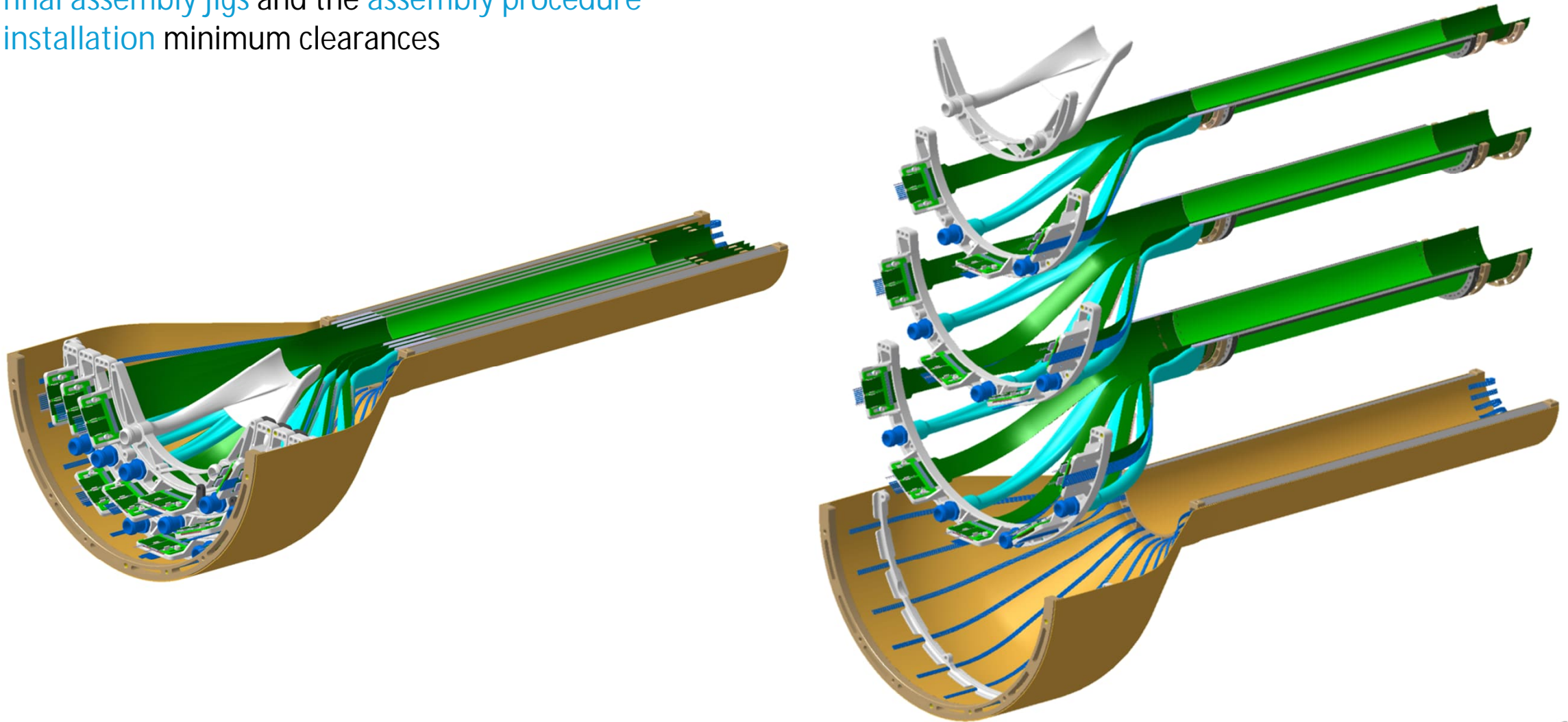


Prototypes: Engineering models



Before the Qualification Models (QMs), minimum **three additional Engineering Models (EMs)** will be constructed, aimed at validating:

- The **layout**, including the **electronics connections** and the **service interface**
- The **final assembly jigs** and the **assembly procedure**
- The **installation** minimum clearances



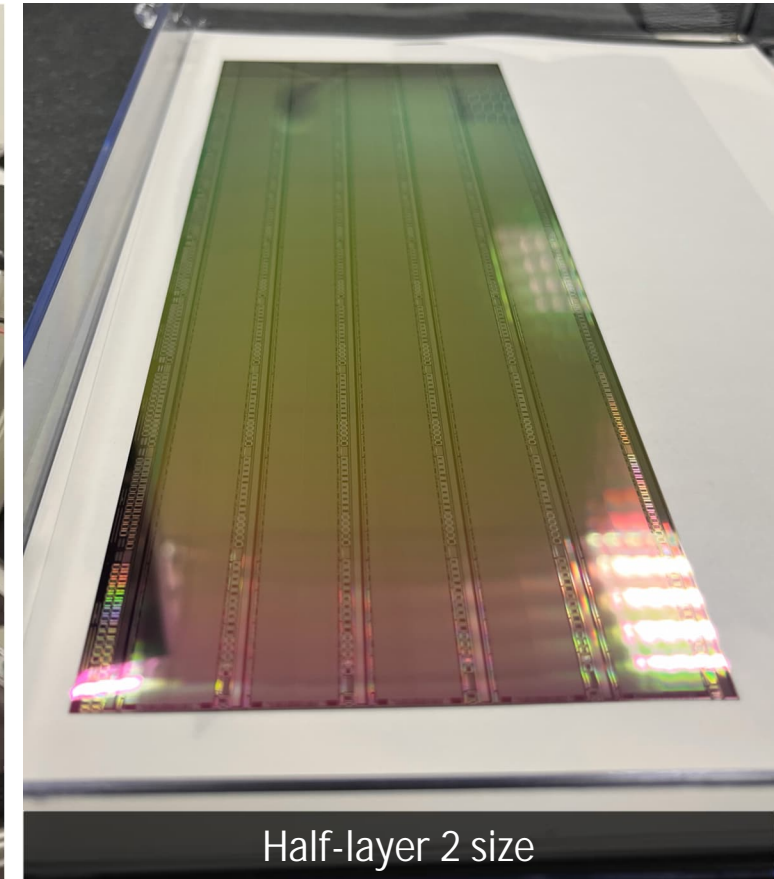
Prototypes: EM3



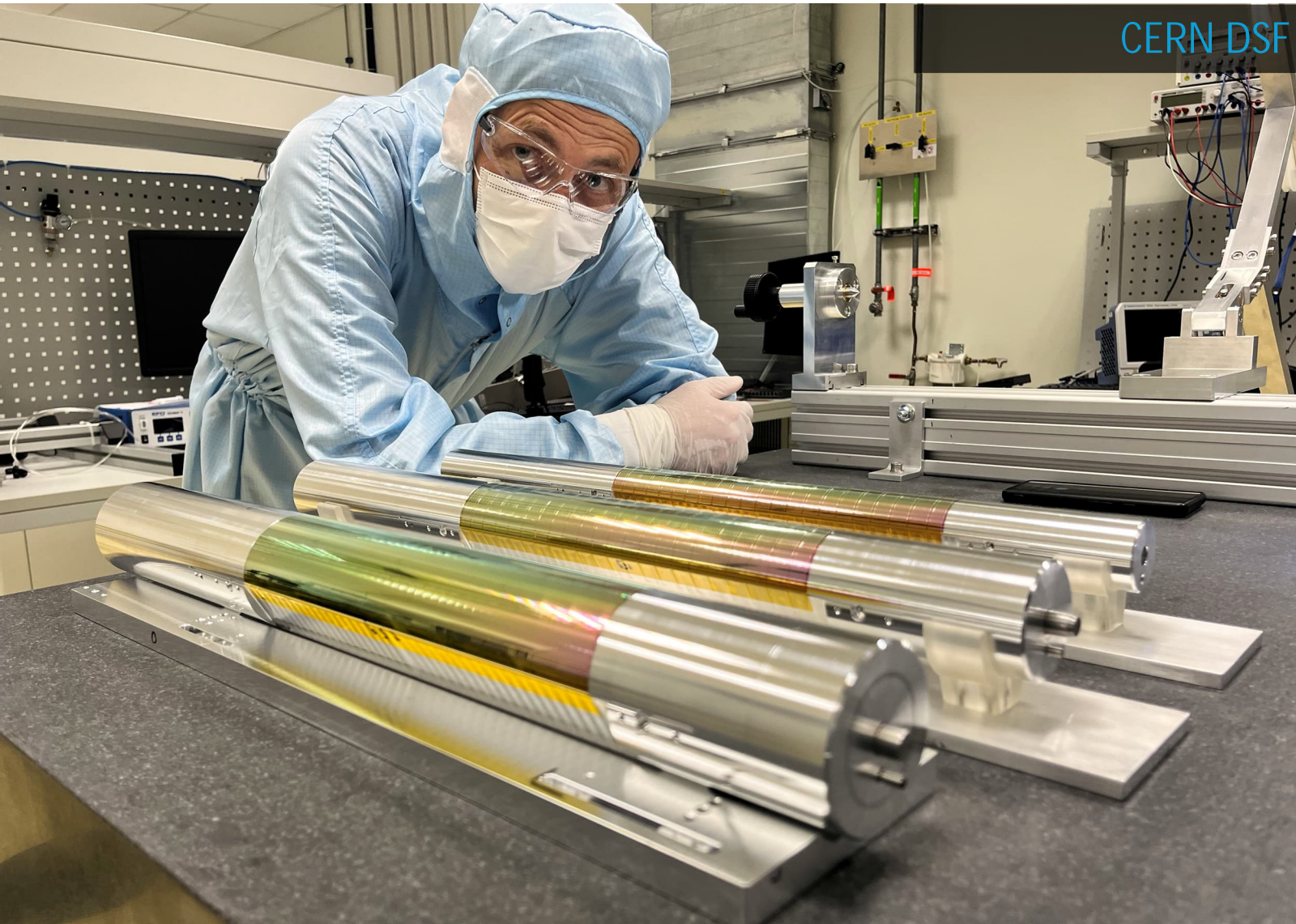
- EM3 was intended to be displayed at the small-exposition for the CERN70th anniversary (Ex EXPO prototype)
- This prototype is intended to [assess the new assembly jigs](#), identify potential additional modifications, and evaluate the [overall sensor integration](#), including services and their routing.
- It integrates half-layer sensors from the ER1 pad wafers, though they do not have the nominal dimensions of the MOSAIX.



Die ejector

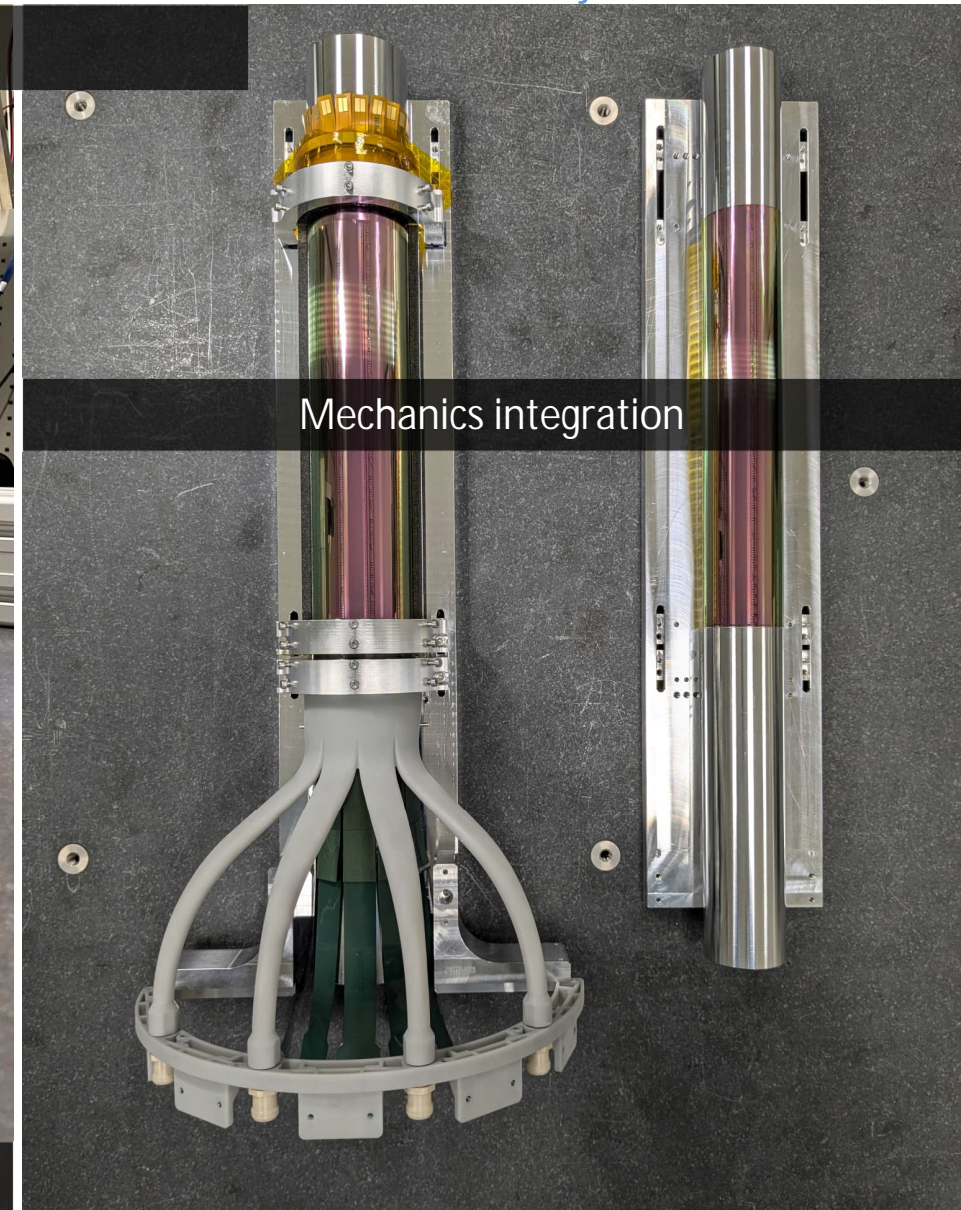


Half-layer 2 size



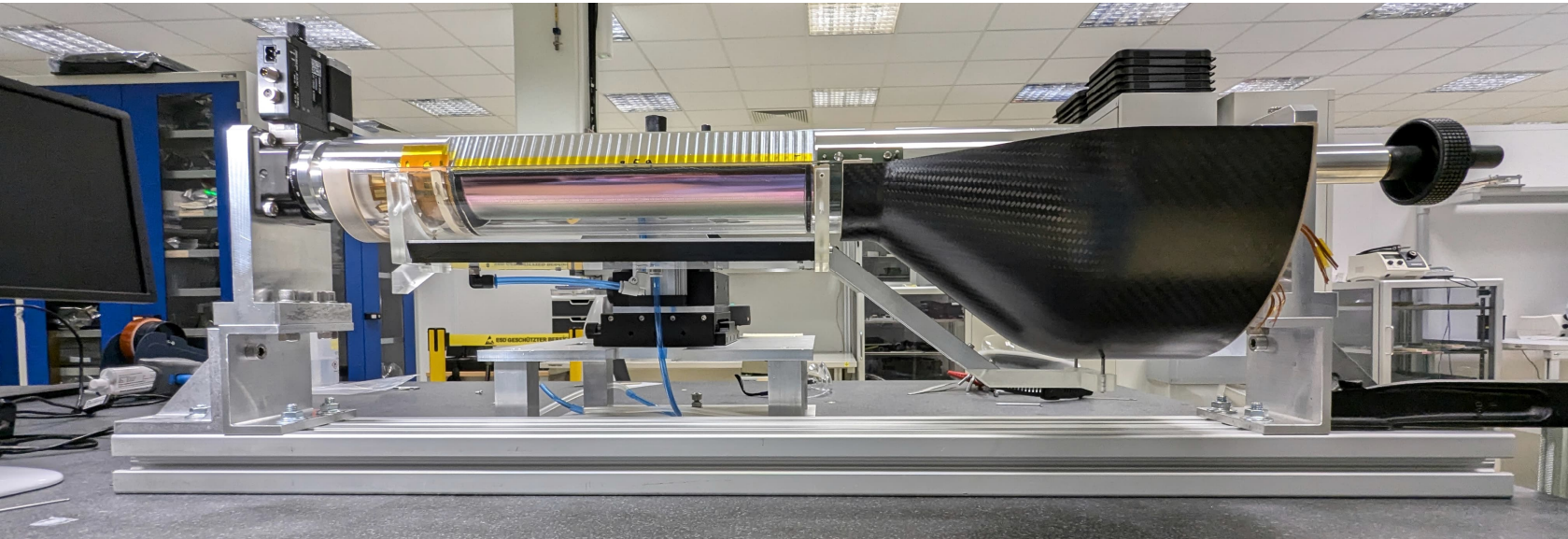
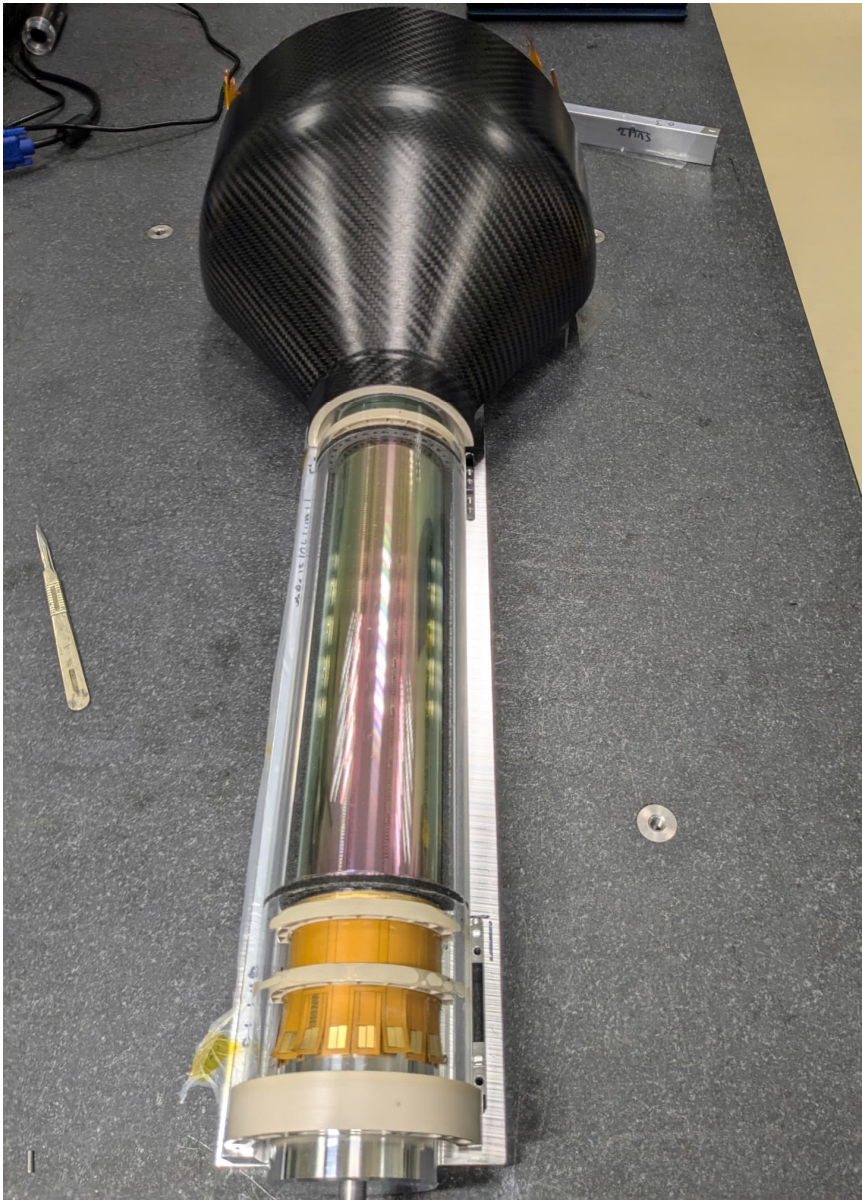
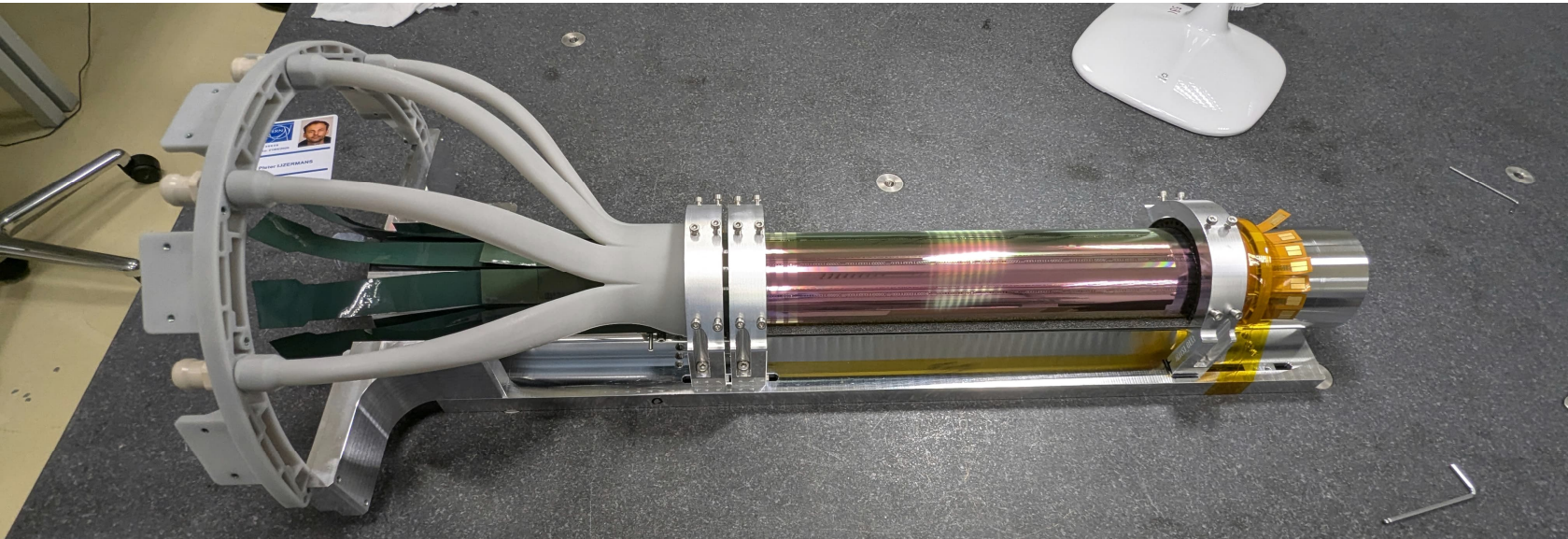
CERN DSF

Bending of the three half-layers (from ER1 pad wafers)



Mechanics integration

Prototypes: EM3, L2 integration

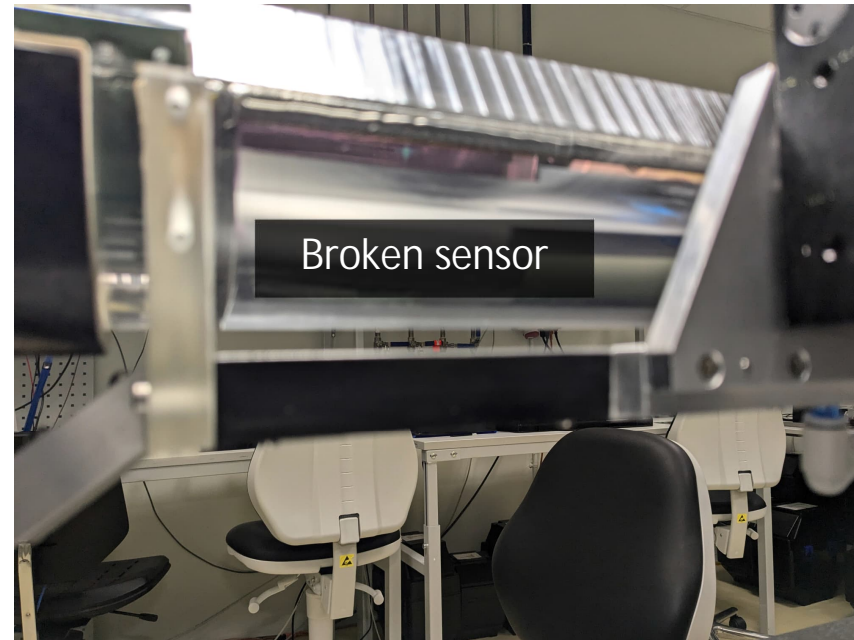
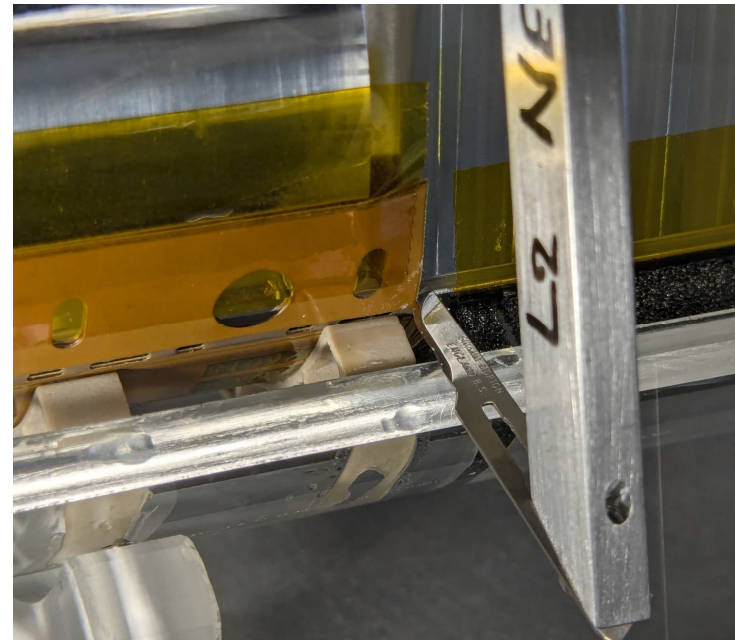


Prototypes: EM3, L2 integration

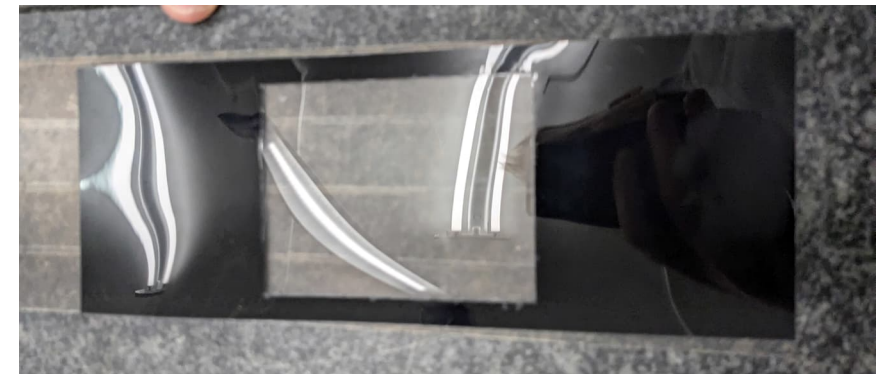


The half-layer 2 sensor broke during the final step of L2 integration into the CYSS, specifically when removing the chip from the mandrel (after cutting the Kapton tape). The failure was due to the sensor's smaller width (approximately 1 mm less) compared to the nominal size. This size difference caused part of the Kapton tape to remain stuck to the mandrel, which constrained the chip along its long edge during removal.

The assembly proceeded with a mylar-based dummy sensor.

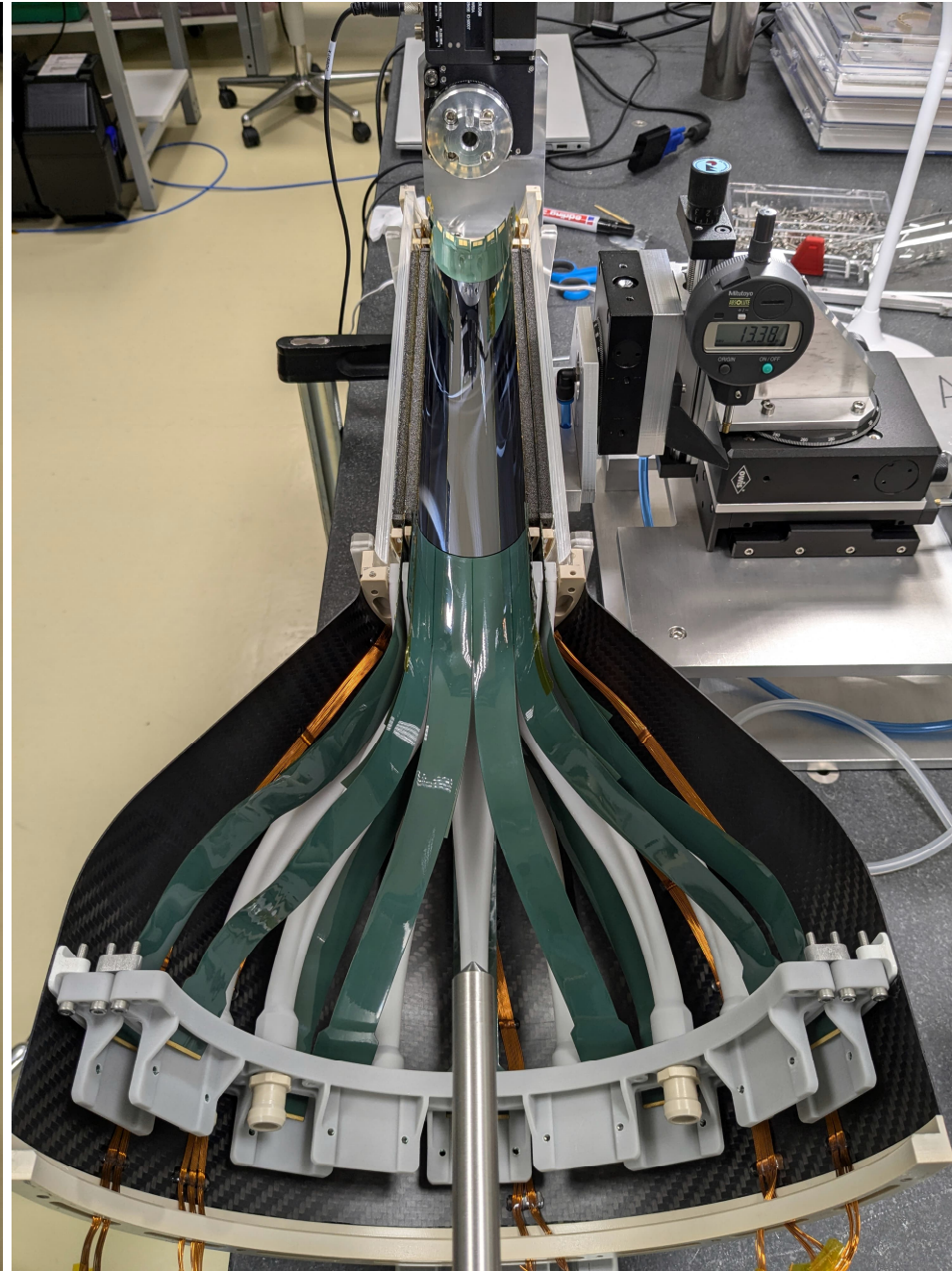


Dummy half-layer 2

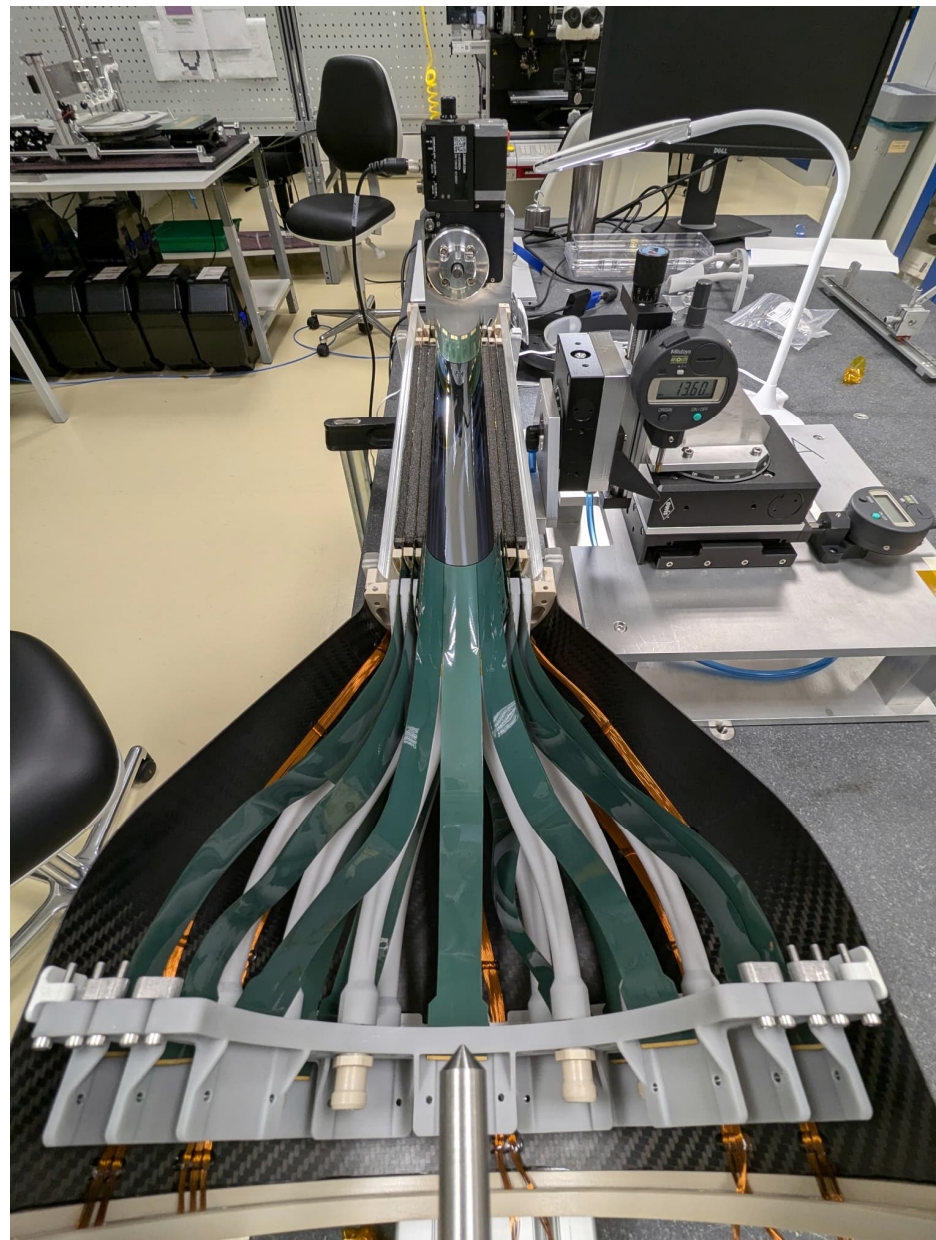
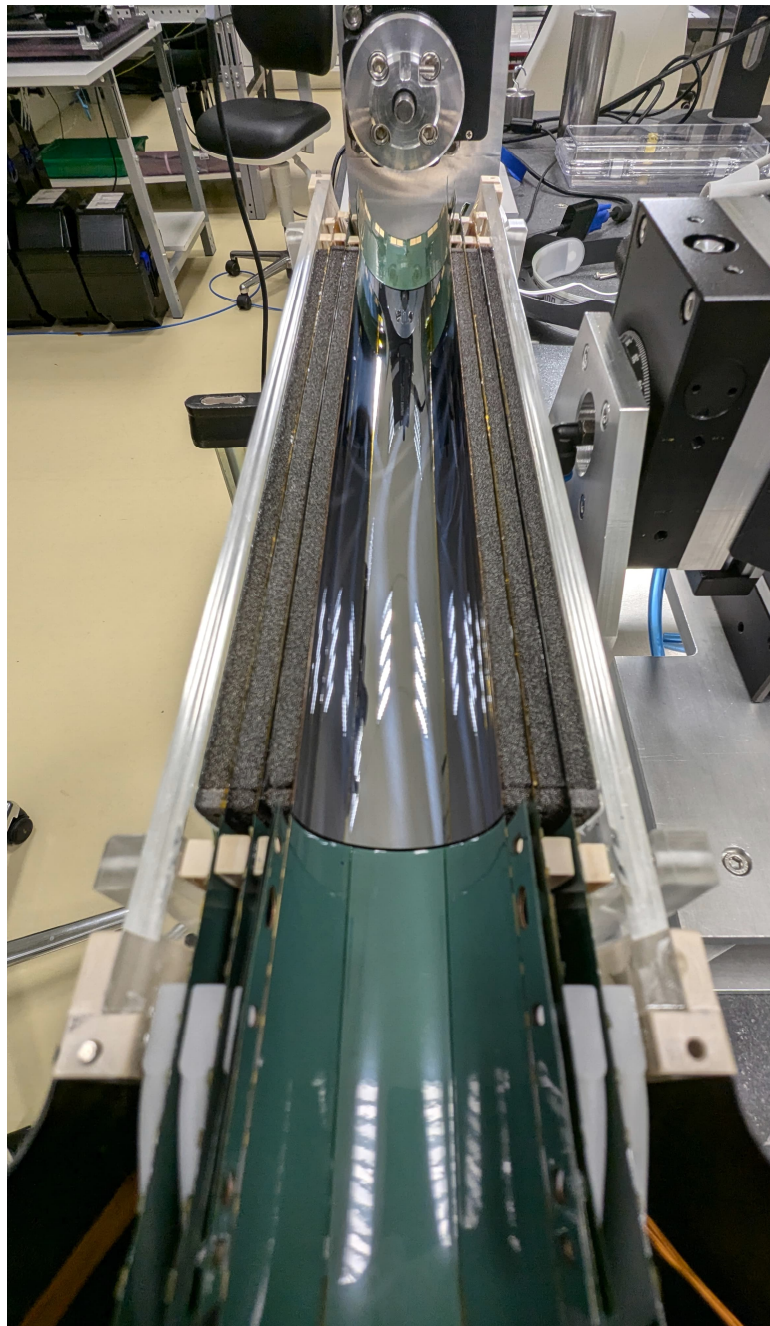
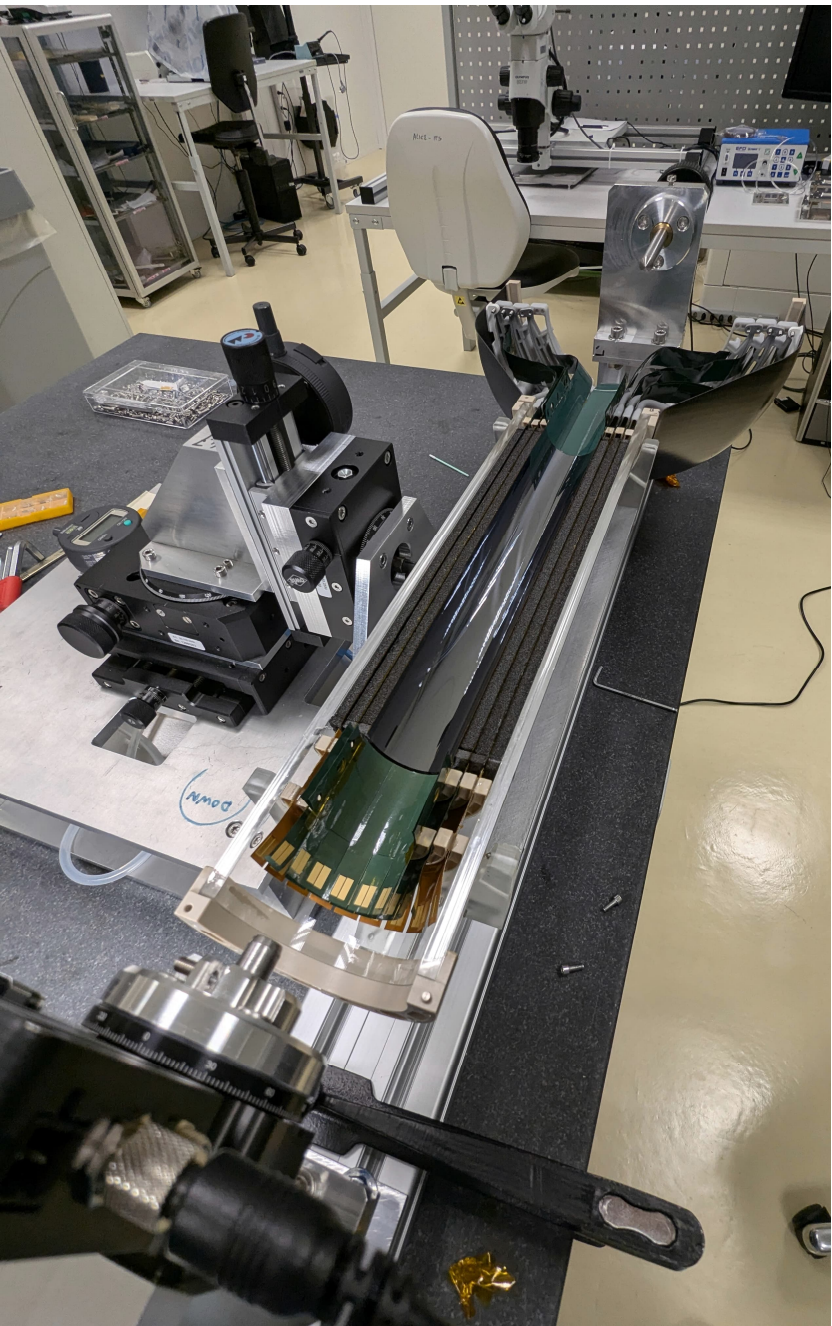


Mylar transparent foil + black thermochromic foil

Status of the new prototype: EM3, L1 integration



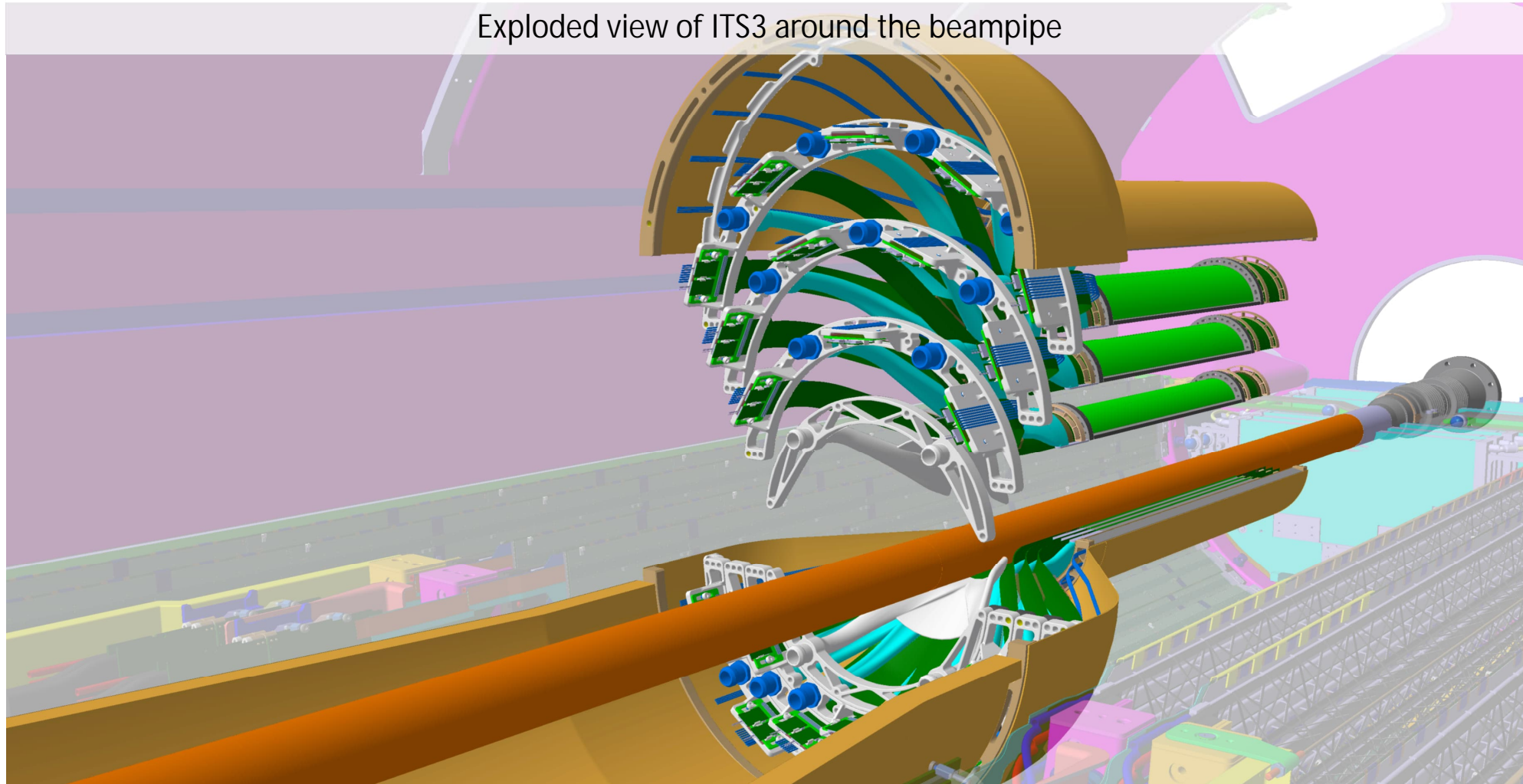
Status of the new prototype: EM3, L0 integration



Prototypes: EM4 and EM5



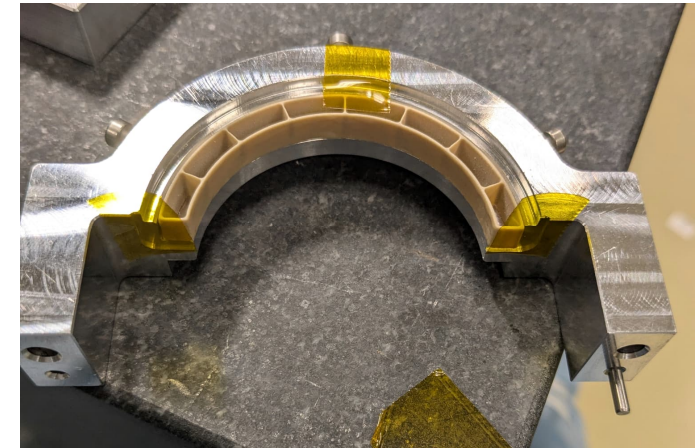
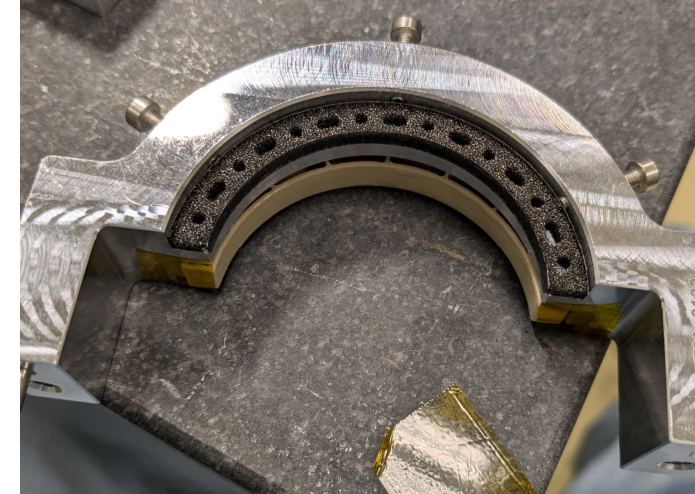
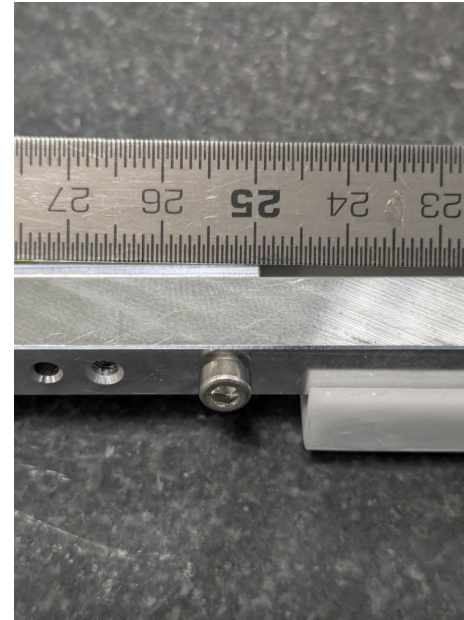
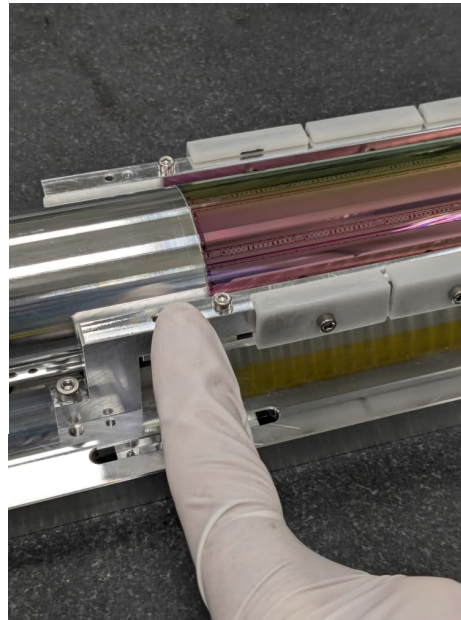
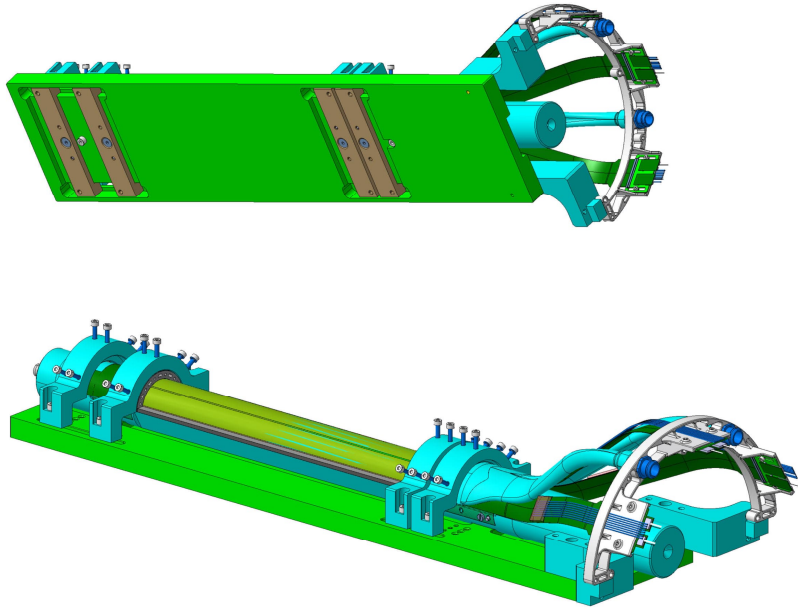
- They will **validate the overall assembly procedure**, including the **wire-bonding step**. In addition, they will be used to preliminary assess the **installation procedure**.
- Depending on which sensors are available at the time of assembly, these prototypes will integrate either dummy MOSAIX (from ER2 pad wafers) or dummy chips from blank wafers with Cr/Al metal deposition for wire-bonding purposes.



Prototypes: EM4 and EM5, assembly jigs



The present assembly jigs were designed to accommodate h-rings of different thicknesses (6 and 3.5 mm) and varying longeron lengths.



- During the assembly of the EM3, valuable experience was gained. This experience highlighted several suggestions for improving the assembly jigs, particularly regarding alignment.
- New jigs (new collars for the h-rings, baseplate for alignment), which will be used for the upcoming engineering models, are currently in the design phase ([@G. Ledey](#))

Prototypes: EM4 and EM5, dummy sensors

@J. B. Van Beelen, EP-DT-TFG

- Dummy chips from blank wafers with Cr/Al metal deposition for wire-bonding purposes.

EP-DT-TFG, Physical Vapour Deposition (PVD)

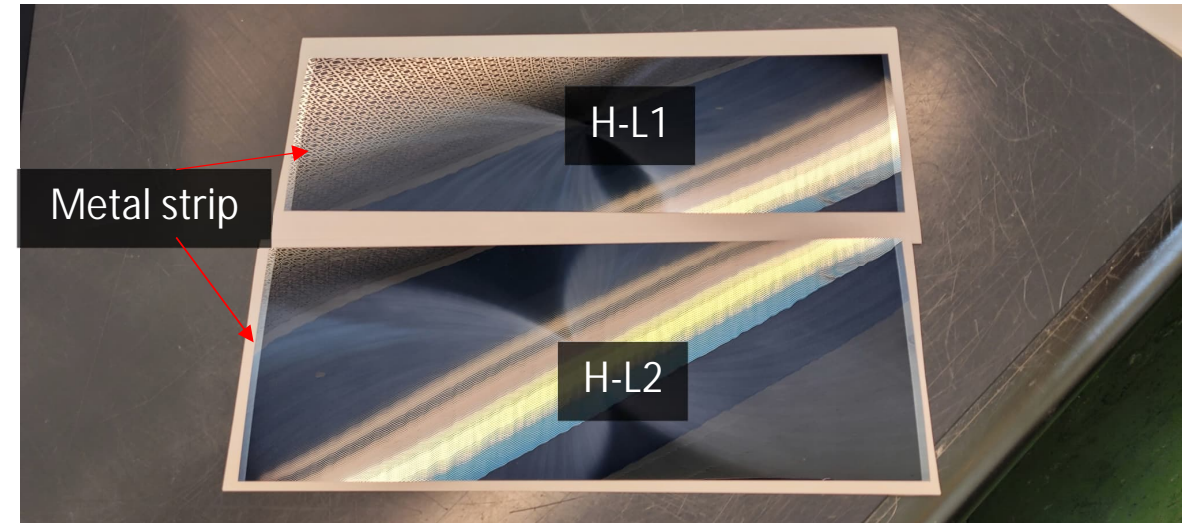
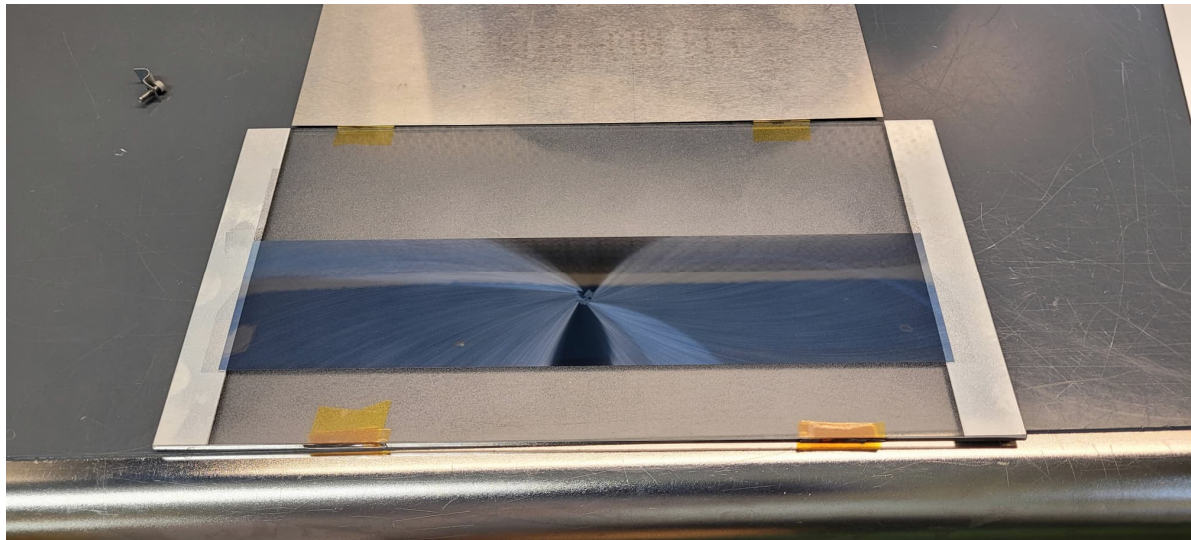
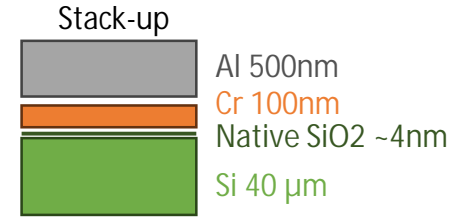
Done:

2x half-layer 2

2x half-layer 1

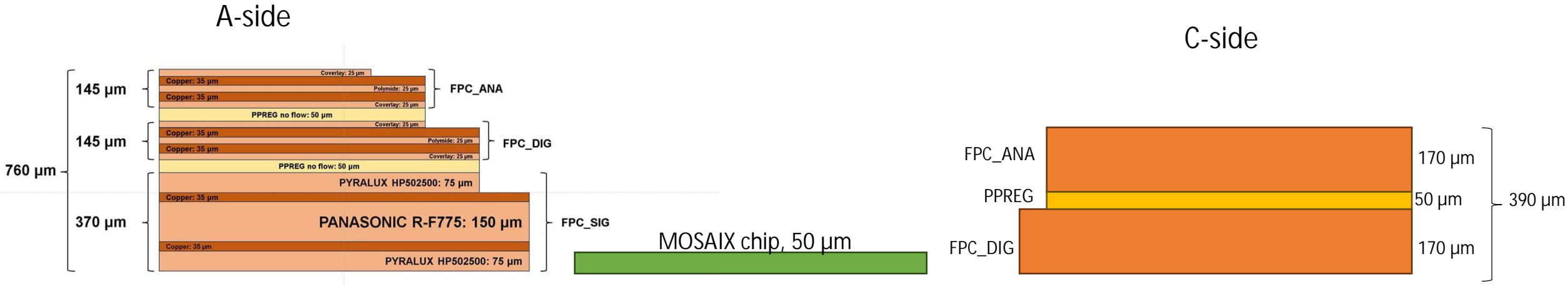
On-going

2x half-layer 0





- Stack-up of the FPCs as of today



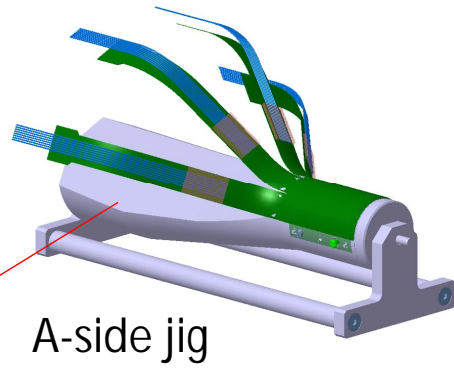
- The new FPC stack-up is thicker and more rigid compared to what was initially proposed in the TDR.
- A new gluing method was necessary due to the specific rigidity of the FPC-Data.
- For the C-side FPCs, the three sub-FPCs will be glued together using an adhesive film that requires high temperature, vacuum, and pressure during the bonding process.
- Similar procedure will be followed for the A-side FPCs
- This gluing process necessitates the use of an autoclave ([@EP-DT Composite lab](#)).
- For this purpose, new gluing jig mandrels were produced ([@L.Mcalpine](#)).
- PEEK H-rings (mechanics support of the FPCs) will be adapted according to FPC thicknesses ([@G. Ledey](#))

FPC updates: assembly jigs

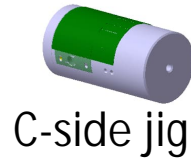


- New jigs for FPC production for gluing/curing in autoclave.

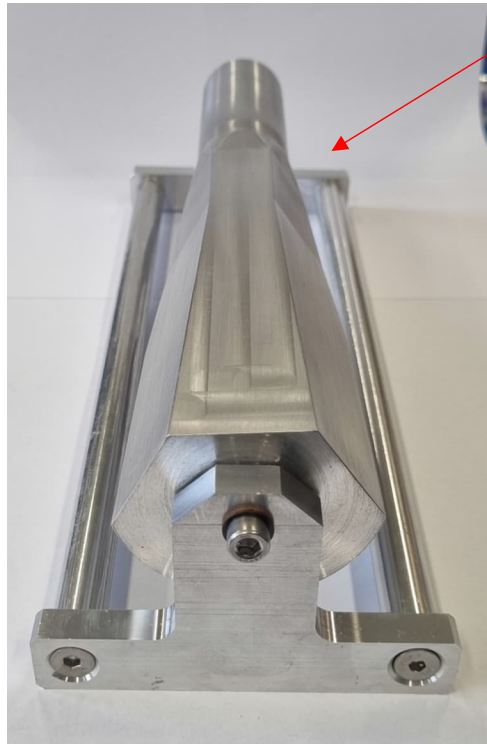
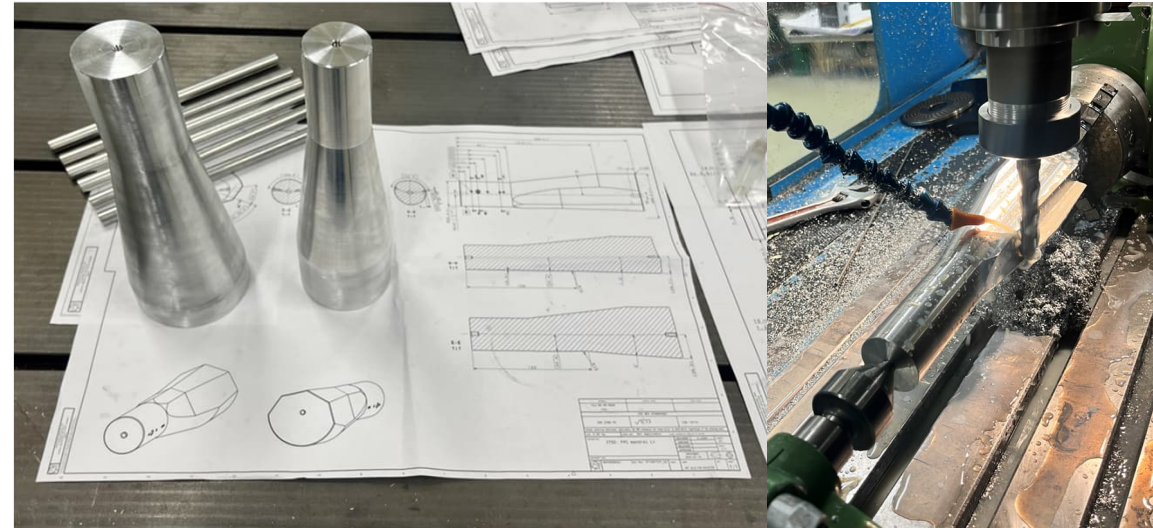
@G. Ledey, L. Mcalpine



A-side jig



C-side jig

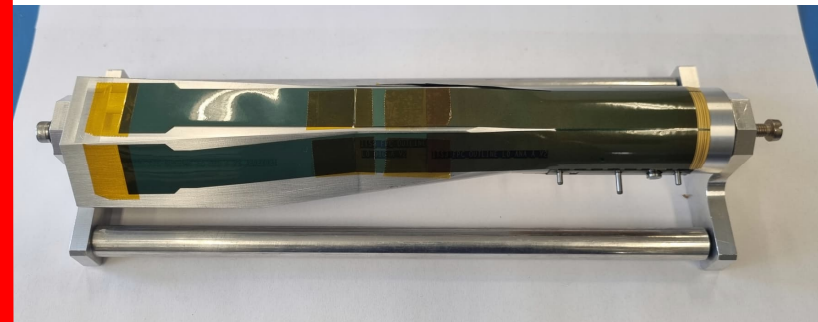
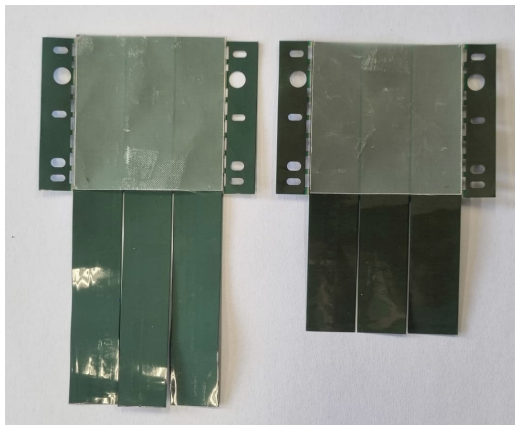
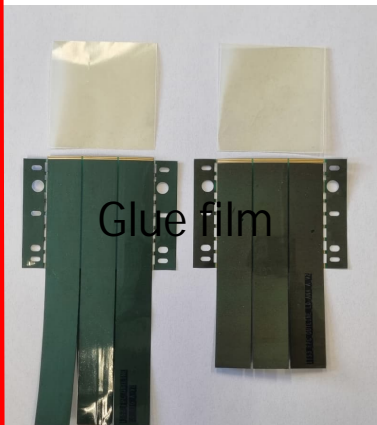
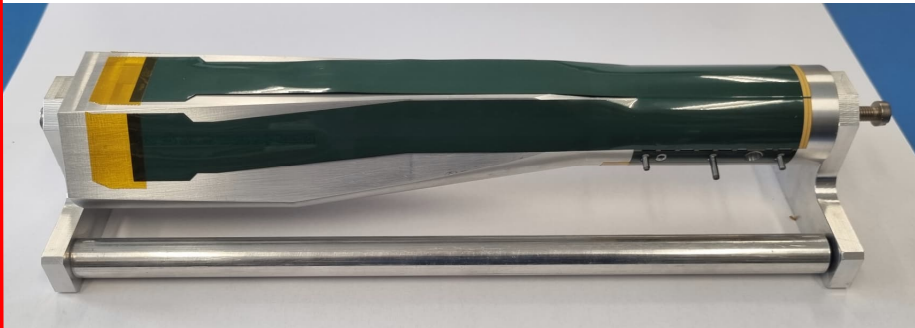
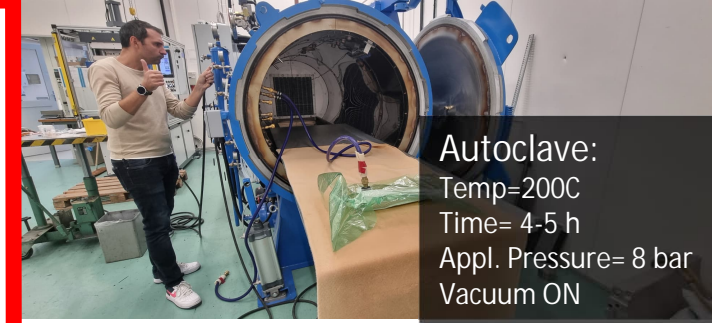


- A set of gluing jig mandrels for the assembly of the A-side FPCs was produced.
- **Next:** production of a set of gluing jigs for the assembly of C-side FPCs

FPC updates: Assembly

- Curing in autoclave: Validated assembly of the FPCs
The photos below show the assembly of a Dummy C-side FPC

@A.Unique, EP-DT Composite Lab



FPC updates: Assembly

- C-Side FPC (L0) with nominal stack-up (total thickness 790 μm) was produced.

@A.Junique, EP-DT Composite Lab



Next: Production of a C-Side FPC (L2) with nominal stack-up.